<table>
<thead>
<tr>
<th>Session Title:</th>
<th>[Tu1E] Dimensional Metrology III</th>
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<td>Session Date:</td>
<td>August 6 (Tue.), 2024</td>
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<tr>
<td>Session Time:</td>
<td>11:00–12:30</td>
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<td>Session Room:</td>
<td>Room E (114)</td>
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<td>Session Chair(s):</td>
<td>Dr. Jonghan Jin (KRISS, Korea)</td>
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### [Tu1E-1] [Invited] 11:00–11:30

**Double-sided Interferometer for SI-traceable Thickness Measurement**

Akiko Hirai and Youichi Bitou (Nat'l Metrology Inst. of Japan, Japan)

### [Tu1E-2] 11:30–11:45

**Application for Wafer Measurement using Multi-channel Laser Ranging based on Dual-comb Time-of-flight with High-efficiency Cross-correlation via Semiconductor Optical Amplifier**

Jaeyoung Jang, Hyeokin Kang, Hyunsu Kim, Seung-Woo Kim, and Young-Jin Kim (KAIST, Korea)

### [Tu1E-3] 11:45–12:00

**Measurement of Temporal Phase of Weak Optical Pulses in a Noisy Environment**

Jerzy Szuniewicz (Univ. of Warsaw, Poland), Steven Sagona-Stophel, Sarah Thomas, Ian Walmsley (Imperial College London, UK), and Michał Karpiński (Univ. of Warsaw, Poland)

### [Tu1E-4] 12:00–12:15

**Phase Noise Measurement with Delay Interferometer During Fast Polarization Fluctuation**

Shiro Ryu (Meiji Univ., Japan)

### [Tu1E-5] 12:15–12:30

**Precise Enhancement for Optical Delay Measurement**

Haoxuan Zhang, Weimeng Wang, Song Yu, Bin Luo, and Tianwei Jiang (Beijing Univ. of Posts and Telecommunications, China)